

Long Title Subtitle

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Introduction and motivation

See Schlosser et al. (2022).

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Fundamentals and implementation

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Test results, evaluation, and discussion

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Conclusion and outlook

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Schlosser, T., Friedrich, M., Beuth, F., and Kowerko, D. (2022). Improving automated visual fault inspection for semiconductor manufacturing using a hybrid multistage system of deep neural networks. *Journal of Intelligent Manufacturing*, 33(4):1099–1123.